

Title (en)

Alarm and control system for semiconductor manufacturing plants.

Title (de)

Alarm- und Steuerungssystem einer Herstellungsanlage für Halbleiter.

Title (fr)

Système d'alarme et de commande pour installation de fabrication de semi-conducteurs.

Publication

**EP 0112492 A2 19840704 (EN)**

Application

**EP 83111572 A 19831119**

Priority

JP 20688882 A 19821127

Abstract (en)

This invention relates to an alarm and control system for semiconductor manufacturing plants which is capable of detecting the leaking processing gas both in gaseous state and in a state that it is generating combustion products as a result of its reaction with oxygen in air and combustion, and of performing adequate controls before or in incipient stage of fire.

IPC 1-7

**G08B 17/10**

IPC 8 full level

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CPC (source: EP)

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Cited by

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**EP 0112492 A2 19840704**; **EP 0112492 A3 19870826**; **EP 0112492 B1 19900110**; DE 3381099 D1 19900215; ES 527814 A0 19850416; ES 8505125 A1 19850416; JP S5998293 A 19840606

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